



Patent  
Attorney's Docket No. 015290-506

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of	)	
	)	
Ting CHIEN et al.	)	Group Art Unit: 1765
	)	
Application No.: 09/820,692	)	Examiner: K.C. Chen
	)	
Filed: March 30, 2001	)	Confirmation No. 5245
	)	
For: PLASMA ETCHING OF DIELECTRIC LAYER	)	
WITH SELECTIVITY TO STOP LAYER	)	
	)	

**AMENDMENT AFTER FINAL REJECTION**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed October 7, 2003, please amend the  
above-identified application as follows:

**RECEIVED**  
FEB 19 2004